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PATENT NUMBER and
ISSUE DATE

U.S. UTILITY Patent Application

APPL NUM 10030656	FILING DATE 01/11/2002	CLASS 216	SUBCLASS 1763	GAU 1763	EXAMINER Olsen
**APPLICANTS: Hagihara Masaaki; Inazawa Koichiro; Naito Wakako; 1763					
**CONTINUING DATA VERIFIED: THIS APPLICATION IS A 371 OF PCT/JP00/05624 08/23/2000					
** FOREIGN APPLICATIONS VERIFIED: JAPAN 11/2411427 08/27/1999					
PG-PUB <input type="checkbox"/>		DO NOT PUBLISH <input type="checkbox"/>		RESCIND <input type="checkbox"/>	
Foreign priority claimed <input checked="" type="checkbox"/> yes <input type="checkbox"/> no 35 USC 119 conditions met <input checked="" type="checkbox"/> yes <input type="checkbox"/> no Verified and Acknowledged Examiners's initials <i>AW</i>				ATTORNEY DOCKET NO 07553.0029	
TITLE : Method of etching and method of plasma treatment					

U.S. DEPT. OF COMMERCE PAT. & TM. PTO-4361 (Rev. 12-94)

NOTICE OF ALLOWANCE MAILED		CLAIMS ALLOWED	
		Total Claims	
		Print Claim for O.G.	
ISSUE FEE		DRAWING	
Amount Due	Date Paid	Sheets Drwg.	Figs. Drwg.
		Print Fig.	
<input type="checkbox"/> TERMINAL		Application Examiner	
DISCLAIMER		PREPARED FOR ISSUE	
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